	Search Text	DBs	Time Stamp		
1		USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 15:59		
2	PR or photoresist or resist or ARC or (anti-reflective adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)	US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/11/09 16:01		
3	plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 16:02		
4	singl\$4 or complet\$4 or "one step" or "single step"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 16:03		
5	or	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 16:05		

	Search Text	DBs	Time Stamp		
6	((etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask") near4 (PR or photoresist or resist or ARC or (anti-reflectiv e adj coating) or (antiaedj or (antiadj reflective adj coating)) near8 plasma near8 (singl\$4 or complet\$4 or "one step" or "single step")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 16:05		
7	((etch adj stop\$4) or (hard adj mask) or "hard mask") near8 (PR or photoresist or resist or ARC or (anti-reflectiv e adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)) near8 plasma near8 (singl\$4 or complet\$4 or "one step" or "single step")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/09 16:07		

					
	Search Text	DBs	Time Stamp		
8	or	USPAT; US-PGPUB; EPO;	2003/11/10 09:42		
9	((etch adj stop\$4) or (ctchstop\$4 or (hard adj mask) or "hard mask") same (PR or photoresist or resist or ARC or (anti-reflective adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)) same plasma same (singl\$4 or complet\$4 or "one step" or "single step")	USPAT; US-PGPUB; EPO; JPO; DERWENT;	2003/11/10 09:43		

	Search Text	DBs	Time Stamp	
10	(((etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask") same (PR or photoresist or resist or ARC or (anti-reflectiv e adj coating) or (antireflectiv e adj coating) or (anti adj reflective adj coating)) same plasma same plasma same (singl\$4 or complet\$4 or "one step" or "single step")) not (((etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask") near4 (PR or photoresist or	US-PGPUB; EPO; JPO; DERWENT;	2003/11/10 09:43	
11	(438/717).CCLS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/10 10:44	
12	(438/697).CCLS	JPO; DERWENT; IBM_TDB	2003/11/10 11:39	
13	(438/694).CCLS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/10 13:46	
14	(438/695).CCLS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/10 13:50	
15	(438/709).CCLS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/11/10 14:28	

	Search Text	DBs	Time Stamp
16	(438/738).CCLS		2003/11/10 15:33

	Туре	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L5	19342	(etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask"	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 15:59
2	BRS	L6	783392	PR or photoresist or resist or ARC or (anti-reflective adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:01
3	BRS	L7	356204	plasma	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:02
4	BRS	L9	379232 9	singl\$4 or complet\$4 or "one step" or "single step"	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:03
5	BRS	L12	127	5 near4 6 near8 7	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09

	Туре	L #	Hits	Search Text	DBs	Time Stamp
6	BRS	L15	372	5 same 6 same 7 same 9	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:05
7	BRS	L16	1711	5 same 6 same 7	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:05
8	BRS	L13	5		USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09 16:05
9	BRS	L14	12		USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/09

	Туре	L #	Hits	Search Text	DBs	Time Stamp
1	BRS		127	((etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask") near4 (PR or photoresist or resist or ARC or (anti-reflective adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)) near8 plasma	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/10 09:42
2	BRS	L2	372	((etch adj stop\$4) or etchstop\$4 or (hard adj mask) or "hard mask") same (PR or photoresist or resist or ARC or (anti-reflective adj coating) or (antireflective adj coating) or (anti adj reflective adj coating)) same plasma same (singl\$4 or complet\$4 or "one step" or "single step")	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/10 09:43
3	BRS	L3	346	2	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2003/11/10 09:43